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Substitute for form 1449A/PTO

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

(use as many sheets as necessary)

Sheet 1

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Complete if Known

Application Number	09/699,614
Filing Date	10/30/2000
First Named Inventor	Silver RECEIVED
Group Art Unit	2621 OCT 23 2001
Examiner Name	Not Known
Attorney Docket Number	C00-057 Technology Center 2600

U.S. PATENT DOCUMENTS

FOREIGN PATENT DOCUMENTS

Examiner Signature	<i>Frank</i>	Date Considered	10/22/03
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¹Unique citation designation number. ²See attached Kinds of U.S. Patent Documents. ³Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number. ⁵Indicate document by the two-letter code which is indicated on the document by the WIPO Standard ST.12.

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Substitute for form 1449B/PTO

Complete if Known**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(use as many sheets as necessary)

Application Number 09/699,614**Filing Date** 10/30/2000**First Named Inventor** Silver**Group Art Unit** 2854**Examiner Name** Not Known**RECEIVED**

OCT 23 2001

Sheet

2

of

2

Attorney Docket Number

C00-057

Technology Center 2600

OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials*	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
BL		KLA-TENCOR, INC., Candidate Alignment Target For Wafer, 1997	
		DAVID I. HAVERLOCK, Geometric Precision in Noise-Free Digital Images, IEEE Transactions on Pattern Analysis and Machine Intelligence, VOL. II No 10. October 1989	
		JOHN W. HILL, Machine Intelligence Research Applied To Industrial Automation, National Technical Information Service, U.S. Department of Commerce, November 1980	
		CHINMOY B. BOSE AND ISREAL AMIR, Design of Fiducials for accurate Registration Using Machine Visions, IEEE Transaction on Pattern Analysis and Machine Intelligence, VOL. 12 No. 12, December 1990	
		LAWRENCE O'GORMAN, Subpixel Precision of Straight-Edged Shapes for Registration and Measurement, IEEE Transactions on Pattern Analysis and Machine Intelligence, VOL. 18, No. 7 1996	
		H.F. GILLESPIE AND J.E. MARTIN, Optimization of Optical Alignment Marks Through Circuit Design Rule Consideration, Rockwell International, Newport Beach, CA, 1978	
		NEAL T. SULLIVAN, Semiconductor Pattern Overlay, Digital Equipment Corp., Advanced Semiconductor Development	
		HIDEKI INA, KOICHI SENTOKU AND TAKAHIRO MATSUMOTO (Nanotechnology research Center) - HIROAKI SUMITANI AND MUNHEYOSHI SUITA (Advanced Technology R&D Center, Alignment Mark Optimization to Reduce Tool and Wafer Induced Shift for XRA-1000	
		W. MAKOUS, Optimal Patterns For Alignment, Applied Optics Vol. 13, No. 3, March 1974	
		EGIL D. CASTEL and NADER SHAMMA, Design and Optimization of Site-By-Site Alignment Marks for a Single Polysilicon Bipolar Process, National Semiconductor Corporation, Elsevier Science Publishers B.V.	
BL		ALFRED M. BRUCKSTEIN, LARRY O'GORMAN AND ALON ORLITSKY, Design of Shapes for Precise Image Registration, IEEE Transactions on Information Theory, VOL. 44, No. 7, November 1998	

Examiner Signature

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Date Considered

10/22/03

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.

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